## <sup>4B2/2005G157, 2005G158, 2006G263, 2006G264</sup> Experimental and Theoretical Evidence for the Covalent Bonding and Charge Transfer in α-Silicon Nitride, A Synchrotron Diffraction Study

Masatomo YASHIMA,<sup>1,\*</sup> Yoshiaki ANDO<sup>1</sup> and Yasunori TABIRA<sup>2</sup> <sup>1</sup> Department of Materials Science and Engineering, Interdisciplinary Graduate School of Science and Engineering, Tokyo Institute of Technology, 4259 Nagatsuta-cho, Midori-ku, Yokohama, Kanagawa, 226-8502, Japan; <sup>2</sup> Corporate R & D Center, Mitsui Mining & Smelting Co. Ltd., Haraichi 1333-2, Ageo-shi, Saitama, 362-0021, Japan

## **Introduction**

Silicon nitride  $(Si_3N_4)$  continues to attract many researchers because of interesting mechanical and dielectric properties. The purpose of this work is to study the electron-density distribution of  $\alpha$ -Si<sub>3</sub>N<sub>4</sub> using synchrotron powder diffraction data. Density functional theory (DFT) is employed to calculate the electron density distribution and elastic properties. The covalent bonding between the Si and N atoms is observed in the experimental electron-density distribution of  $\alpha$ -Si<sub>3</sub>N<sub>4</sub> for the first time in the present study (Yashima *et al., J. Phys. Chem. B*, **111**, 3609 (2007)).

## **Experiments**

Synchrotron x-ray powder diffraction experiments of a commercial silicon nitride material were performed at 299 K using the multiple-detector system installed at the BL-4B<sub>2</sub> beam line of the Photon Factory, High Energy Accelerator Research Organization (KEK), Japan. A monochromatized 1.20490(1) Å x-ray beam was utilized. The crystal structures of the silicon nitrides were refined by the Rietveld method with a computer program RIETAN-2000 (Izumi & Ikeda, 2000). Electron-density distribution of  $\alpha$ -Si<sub>3</sub>N<sub>4</sub> was investigated by a maximum-entropy method (MEM, PRIMA (Izumi & Dilanian, 2002)) and DFT calculations.

## **Results and discussion**

All the reflection peaks in the synchrotron powder diffraction pattern of the present silicon nitride powders were indexed by the  $\alpha$ - and  $\beta$ -Si<sub>3</sub>N<sub>4</sub> phases. Space groups *P*31*c* and *P*6<sub>3</sub>/*m* were assumed for the  $\alpha$ - and  $\beta$ -Si<sub>3</sub>N<sub>4</sub>, respectively. Weight fractions of  $\alpha$ - and  $\beta$ -Si<sub>3</sub>N<sub>4</sub> calculated using the refined crystallographic parameters and scale factors were 0.975 and 0.025, respectively. In combination with density functional theory (DFT) calculations, the present experimental electron-density distribution of the  $\alpha$ -Si<sub>3</sub>N<sub>4</sub> indicates covalent bonds between Si and N atoms and the charge transfer from the Si to N atom (Fig. 1). The MEM experimental electron density is consistent with the theoretical DFT valence electron density. The triangular distribution around N atoms was found in both experimental and theoretical electron density distributions, which is attributable to the nitrogen  $sp^2$  hybridization for the nearest silicon and nitrogen pairs. The minimum electron density in an intralayer Si-N bond was a little lower than that in an interlayer bond, which would be responsible for the inequality between elastic constants  $C_{33} > C_{11}$ . The present work suggests that the high bulk modulus of the  $\alpha$ -Si<sub>3</sub>N<sub>4</sub> is attributable to the high minimum electron density of the Si-N bond.



**Fig.1**. Projected MEM and valence electron density distributions in  $\alpha$ -Si<sub>3</sub>N<sub>4</sub> (0.3 < z < 0.7) obtained through (a) MEM analysis of synchrotron diffraction data and (b) DFT calculations, respectively. Contour lines from 6 to 40 eÅ<sup>-3</sup> by the step of 5 eÅ<sup>-3</sup>.

\* Corresponding author e-mail address: yashima@materia.titech.ac.jp